



Sheet 1 of 4

LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

Atty Docket No. ACT-214	Serial No. 10/067,218
Applicant Dan A. STEINBERG	
Filing Date February 7, 2002	Group 2874

U.S. Patent Documents

EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	Class/Subclass	FILING DATE IF APPROPRIATE
<i>Ek</i>	AA	4,225,213	09/30/1980	McBride, Jr. et al.		
	AB	4,253,735	03/03/1981	Kawamura et al.		
	AC	4,362,367	12/07/1982	Hammer et al.		
	AD	4,411,057	10/25/1983	Duda et al.		
	AE	4,812,002	03/14/1989	Kato et al.		
	AF	4,830,450	05/16/1989	Connell et al.		
	AG	4,863,560	09/05/1989	Hawkins		
	AH	4,938,841	07/03/1990	Shahar et al.		
	AI	4,957,592	09/18/1990	O'Neill		
	AJ	5,024,500	06/18/1991	Stanley et al.		
<i>Ek</i>	AK	5,095,386	03/10/1992	Scheilbengraber		

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	Class/Subclass	Translation Yes/No
	AL				
	AM				
	AN				
	AO				
	AP				

OTHER ART (Including Author, Title, Date, Pertinent Patents, etc.)

<i>Ek</i>	AQ	Fundamentals of Microfabrication; Marc Madou; CRC Press; 1997, 174-178
	AR	J. Brugger et al.; Self-aligned 3D shadow mask technique for patterning deeply recessed surfaces of micro-electro-mechanical systems devices; Sensors and Actuators 76; 1999; 329-334
<i>Ek</i>	AS	J.D. Fleming; Combining the best of bulk and surface micromachining using Si {111} substrates; SPIE Vol. 3511, September 1998; 162-168

Examiner

Ellen Kim

Date Considered

2/19/02

*EXAMINER: Initial reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not conformance and not considered. Include copy of this form with next communication to applicant.



Sheet 2 of 4

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U.S. Patent Documents

EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	Class/Subclass	FILING DATE IF APPROPRIATE
<i>EC</i>	AT	5,135,590	08/04/1992	Basavanhally et al.		
	AU	5,281,301	01/25/1994	Basavanhally		
	AV	5,338,400	08/16/1994	Jerman		
	AW	5,357,593	10/18/1994	Boassler		
	AX	5,381,231	01/10/1995	Tu		
	AY	5,844,723	10/01/1998	Snyder		
	AZ	5,896,481	04/20/1999	Beranek et al.		
	BA	5,911,021	06/08/1999	MacDonald et al.		
	BB	6,023,546	02/08/2000	Tachigori		
	BC	6,088,168	07/11/2000	Snyder		
<i>EC</i>	BD	6,187,515	02/13/2001	Tran et al.		

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	Class/Subclass	Translation Yes/No
	BE				
	BF				
	BG				
	BHI				
	BI				

OTHER ART (Including Author, Title, Date, Pertinent Patents, etc.)

<i>EC</i>	BJ	Etching of silicon in alkaline solutions: a critical look at the {111} minimum; A. Jasper Nijdam et al.; MESA Research Institute for Micro Electronics, Materials Engineering, Sensors & Actuators <i>No date</i>
	BK	New design methodologies in <111> oriented silicon wafers; R.E. Oosterbroek et al.; MESA Research Institute for Micro Electronics, Materials Engineering, Sensors & Actuators <i>No date</i>
<i>EC</i>	BL	Simulation of Anisotropic Wet-Chemical Etching Using a Physical Model; J. van Suchtelen et al.; MESA Research Institute for Micro Electronics, Materials Engineering, Sensors & Actuators <i>No date</i>

Examiner <i>ellen Korn</i>	Date Considered <i>2/19/04</i>
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Sheet 3 of 4

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U.S. Patent Documents

EXAMINER INITIALS		DOCUMENT NUMBER	DATE	NAME	Class/Subclass	FILING DATE IF APPROPRIATE
<i>EF</i>	BM	2002/0195417	12/26/2002	Steinberg		
	BN	2003/0020130	01/30/2003	Steinberg et al.		
	BO	2003/0034438	02/20/2003	Sherrer et al.		
	BP	2003/0059622	03/27/2003	Steinberg et al.		
	BQ	2003/0067049	04/10/2003	Steinberg et al.		
	BR	4,706,061	11/11/1987	Johnson		
	BS	4,784,721	11/15/1988	Holmen et al.		
	BT	4,837,129	06/06/1989	Frisch et al.		
	BU	4,945,400	07/31/1990	Blonder et al.		
	BV	5,384,872	01/24/1995	Jacobs-Cook et al.		
<i>EF</i>	BW	5,507,911	04/16/1996	Greiff		

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	Class/Subclass	Translation Yes/No
/	BX					
	BY					
	BZ					
	CA					
	CB					

OTHER ART (Including Author, Title, Date, Pertinent Patents, etc.)

	CC	
	CD	
	CE	

Examiner

Ellen Kim

Date Considered

2/19/02

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